

Figure 1

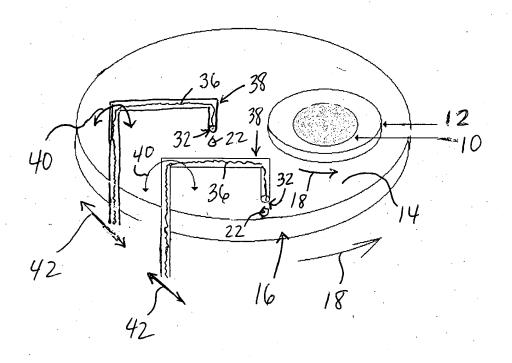


Figure 2

rotating at least one of the wafer carrier and the polishing table, and preferably both

dispensing a chemical (i.e., a slurry) through at least one outlet to the polishing pad

moving the at least one outlet while dispensing the chemical, such as by moving one or more moveable arms in an arc or back and forth motion

Figure 3